

Form PTO-14/9 INFORMATION DISCLOSURE CITATION IN AN APPLICATION <i>(Use several sheets if necessary)</i>			Docket Number (Optional) AMY-002.01 (21424-201)	Application Number 10/079,985		
			Applicant Hiro Tamura, et al.			
			Filing Date February 21, 2002	Group Art Unit		
U.S. PATENT DOCUMENTS						
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
AA	US 6,327,855 B1	12/11/01	Hill et al.	60	528	
AB	US 6,324,748 B1	12/04/01	Dhuler et al.	29	622	
AC	US 6,308,631 B1	10/30/01	Smith et al.	102	254	
AD	US 6,300,619 B1	10/09/01	Aksyuk et al.	250	216	
AE	US 6,285,504 B1	09/04/01	Diemeer	359	578	
AF	US 6,265,239 B1	07/24/01	Aksyuk et al.	438	52	
AG	US 6,262,463 B1	07/17/01	Miu et al.	257	414	
AH	US 6,255,757 B1	07/03/01	Dhuler et al.	310	307	
AI	US 6,246,826 B1	06/12/01	O'Keefe et al.	385	140	
AJ	US 6,222,954 B1	04/24/01	Riza	385	18	
AK	US 6,171,886 B1	01/09/01	Ghosh et al.	438	73	
AL	US 6,173,105 B1	01/09/01	Aksyuk et al.	385	140	
AM	US 6,085,016	07/04/00	Espindola et al.	385	140	
AN	US 6,166,478	12/26/00	Yi et al.	310	328	
AO	US 6,137,941	10/24/00	Robinson	385	140	
AP	US 5,994,816	11/30/99	Dhuler et al.	310	307	
AQ	US 5,909,078	06/01/99	Wood et al.	310	307	
AR	US 5,778,513	07/14/98	Miu et al..	29	602.1	
AS	US 5,629,918	05/13/97	Ho et al.	369	112	
AT	US 6,275,320 B1	08/14/01	Dhuler et al.	359	237	
AU	US 6,163,643	12/19/00	Bergmann et al.	385	140	
AV	US 6,087,743	07/11/00	Guckel et al.	310	40	
AW	US 5,929,542	07/27/99	Ohnstein et al.	310	40	
AX	US 5,808,384	09/15/98	Tabat et al.	310	40	
AY	US 5,644,177	07/01/97	Guckel et al.	310	40	
AZ	US 5,327,033	07/05/94	Guckel et al.	310	40	
BA	US 5,206,983	05/04/93	Guckel et al.	29	598	

Form PTO-1449

**INFORMATION DISCLOSURE STATEMENT
IN AN APPLICATION**
(Use several sheets if necessary)

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Docket Number (Optional)
AMY-002.01 (21424-201)

Application Number
10/079,985

Applicant
Hiro Tamura, et al.

Filing Date
February 21, 2002

Group Art Unit

SEARCHED OTHER DOCUMENTS			<i>(Including Author, Title, Date, Pertinent Pages Etc.)</i>
<i>MH</i>	BB	Bhansali et al.; "Prototype Feedback-Controlled Bidirectional Actuation System for MEMS Applications", Journal of Microelectromechanical Systems, 9 (2): 245-251 (June 2000)	
<i>MH</i>	BC	Stephen Cohen, "Novel VOAs Provide More Speed and Utility", Laser Focus World, pp. 139-146 (November 2000)	
<i>MH</i>	BD	Christenson and Guckel; "An Electromagnetic Micro Dynamometer", 1995 IEEE MEMS Proceedings, Amsterdam, the Netherlands, pp. 386-391, 29 Jan- 2 February, 1995.	
<i>MH</i>	BE	Gong and Zhou, "Micromachined Electromagnetic Actuator", Proceedings of the International Symposium on Test & Measurement, ISTM, PP. 23-26 (1999)	
<i>MH</i>	BF	Guckel et al., "Laterally Driven Electromagnetic Actuators", Solid-State Sensor and Actuator Workshop, Hilton Head, South Carolina, pp. 49-52 (June 13-16, 1994)	
<i>MH</i>	BG	Guckel et al.; "Design and Testing of Planar Magnetic Micromotors Fabricated by Deep X-Ray Lithography and Electroplating", The 7 th International Conference on Solid-State Sensors and Actuators, Yokohama, Japan, pp.76-79, (June 7-10, 1993)	
<i>MH</i>	BH	Guckel et al.; "Fabrication and Testing of the Planar Magnetic Micromotor", J. Micromech. Microeng. 1: 135-138, (1991)	
<i>MH</i>	BI	Guckel et al.; "Electromagnetic, Spring Constrained Linear Actuator with Large Throw", Actuator'94, pp. 52-55, (Bremen, Germany June 15-17, 1994)	
<i>MH</i>	BJ	Guckel et al.; "Micromechanics for Actuators Via Deep X-Ray Lithography", SPIE Vol. 2194, pp. 2-10.	
<i>MH</i>	BK	Guckel et al.; "Processing and Design Considerations for High Force Output- Large Throw Electrostatics, Linear Microactuators", Actuator 94, Bremen, Germany pp. 105-108, (15-17 June 1994) (Abstract)	
<i>MH</i>	BL	H. Guckel and University of Wisconsin, Madison, "Photograph of Actuator," online, retrieved on February 1, 2002 from URL http://mems.engr.wisc.edu/images/linear/intgrated_coil.jpg .	
<i>MH</i>	BM	Guckel et al.; "Micro Electromagnetic Actuators Based on Deep X-Ray Lithography", International Symposium on Microsystems, Intelligent Materials and Robots, Sendai, Japan, September 27-29, (1995) (Abstract)	
<i>MH</i>	BN	Miyajima et al.; "A Durable, Shock-Resistant Electromagnetic Optical Scanner with Polyimide-Based Hinges", Journal of Microelectromechanical Systems 10 (3): 418-424, (September 2001)	
<i>MH</i>	BO	Ohnstein et al.; "Tunable IR Filters with Integral Electromagnetic Actuators", Solid-State Sensor and Actuator Workshop, Hilton Head, South Carolina, pp. 196-199, (June 2-6, 1996)	
<i>MH</i>	BP	Sadler et al.; "A Universal Electromagnetic Microactuator Using Magnetic Interconnection Concepts", Journal of Microelectromechanical Systems 9(4): 460-468, (December 2000)	
<i>MH</i>	BQ	Sadler et al.; "A New Electromagnetic Actuator Using Through-Hole Plating of Nickel/ Iron Permalloy", Electrochemical Society Proceedings volume 98(20): 377-388	

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		Applicant Hiro Tamura, et al.	
		Filing Date February 21, 2002	Group Art Unit
<i>Mjt</i>	BR	Wright et al.; "A Large -Force, Fully-Integrated MEMS Magnetic Actuator", Transducers 97, International Conference on Solid-State Sensors and Actuators, pp. 793-796, (Chicago, June 16-19, 1997)	
			
EXAMINER	<i>Mark Johnson</i>		DATE CONSIDERED <i>05/03</i>
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.			

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